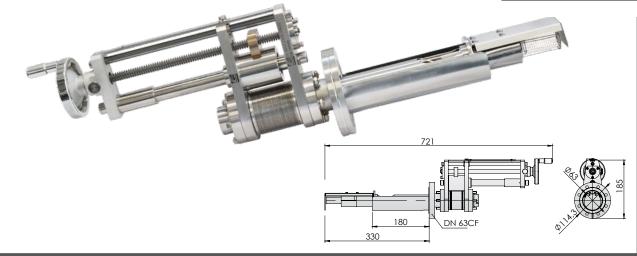
# BEAM FLUX MONITOR





# DESCRIPTION

The Beam Flux Monitor enables measurement of the beam equivalent pressure (BEP) in MBE applications via a Bayard Alpert ionization gauge. It is typically mounted on a linear shift/z-stage to allow the filament to be positioned near to the substrate and includes a protection shield when in the standby position.

## FEATURES

- BEP measurement
- Ion current measurement [nA units]

# OPTIONS

- Motorisation
- Customised insertion length

#### BEAM FLUX MONITOR CONTROL APPLICATION



### TECHNICAL DATA

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Mounting flange	DN 63 CF (non-rotatable)
Measurement system	Bayard-Alpert ion gauge
Measurement range	10 <sup>-3</sup> to 2*10 <sup>-11</sup> Torr
Linear stroke	150 mm (other on request)
Insertion length	180 mm, in standby position (other on request)
Max. outer diameter	63 mm
Filament	dual filament, ytrium coated iridium
Controller	3 channel MG15 - communication interface: RS232/485, Ethernet, PRO-FINET (option - specify at order)
Bakeout temperature	up to 200 °C



Beam Flux Monitor with 200 mm linear stroke.